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The intrinsic piezoresponse in piezoelectric medium under contact-mode piezoresponse force microscopy

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## Highlights

- $\bullet$  The electroelastic fields don't effect  $d^*_{33}$  under individual electromechanical loads
- $d_{33}^*$  has strong correlation with the external loads under contact-mode PFM
- $d_{33}^*$  changes with the geometry of the SPM probe under contact-mode PFM
- The directions of the electric polarizations modulate the magnitude of  $d^\ast_{33}$

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